

http://ecrgroup.lbl.gov



Status of High Current Ion Sources

Daniela Leitner Lawrence Berkeley National Laboratory

October, 27th, 2003





- Overview of available high current sources
- Requirements for underground accelerator
- Why ECR Ion Sources for NUSEL?
- Options for the NUSEL Accelerator
- Beam transport
- Areas for R&D



High current lon sources Brief Overview

- **MEVVA** (Metal Vapor Vacuum Arc Ion Source) **and Laser Evaporation Ion Sources**
 - Medium charge states
 - High currents >100 mA
 - no gases
 - Pulsed
- Multicusp ion sources (Filament/ RF) and cathode based ion sources
 - Single to low charge states
 - High currents >100 mA
 - Limited lifetime

- Microwave Sources
 - Singly Charged Ions
 - High currents >100 mA
 - High Reliability
 - Long Lifetime
- High charge ECR Ion sources (Electron Cyclotron Resonance)
 - Medium to high charge state ions
 - Medium currents (µA to mA)
 - High Reliability
 - Long Lifetime



- High Reliability
- Low Maintenance
- Easy Operation
- Flexibility
 - change charge state to change energy
 - beams from solid material and gases
- Low Power Consumption
 - high voltage Platform
- High Stability

Why are ECR Ion Sources the ideal ion source type for NUSEL?

AECR-U Injector at the 88-Inch Cyclotron as an example



- Runs 24 hours/day, 7 days/ week with minimum intervention
- Minimum maintenance (typically not required for years)
- Excellent Beam Stability
- High Reliability
- High intensities
- High flexibility
- Can produce ion beams from every element
- Good beam quality



How do ECR ion sources work





high charge state ECR ion sources

- high charge states and low charge states
- 10^{-7} to 10^{-6} mbar, total current ≈ 1-5 emA Ar⁸⁺ (2000 eµA) O⁶⁺ (1500 eµA) several mA for light ions
- Beam transport challenging
- R&D area(RIA)

- Single Charged ECR ion source (Chalk River)
 - single charge
 - 10⁻³ to 10⁻² mbar total current up to 130 emA*
 - Beam transport challenging but demonstrated (LEDA)
 - R&D area for high quality beams

*J. Sherman, et. al. *RSI*, vol. 69, pp. 1003, 1998



LEDA has demonstrated > 100 mA H⁺ transported through CW RFQ

low-energy demonstrator accelerator (LEDA)



Proton beam current (mA)	117
Proton fraction(%)	90
Beam energy (keV)	75
Discharge power (W) 2.45 GHZ	600 to 800
Beam noise (%)	±1
lon source emittance (πmm-mrad)	0.13 (rms, normalized)

*J. Sherman, et. al. *RSI*, vol. 69, pp. 1003, 1998



$$\begin{array}{l} \mathbf{n_e} \propto \ \omega_{rf}^2 \\ \tau_{ion} \propto \mathbf{BL}_{mirror} \end{array} \qquad \begin{array}{l} \mathbf{I} \propto \ \omega_{rf}^2 \ \mathbf{M}^{-1} \\ \mathbf{I} \propto \mathbf{P}_{rf}^{-1/3} \end{array}$$





The frequency scaling for the LBNL ECR ion sources







NUS

Produce the world most intense high charge state heavy ion-beams for the 88-Inch Cyclotron





Provide highest current high-charge state beams for the next generation heavy ion accelerators.

VENUS Components





1. Superconducting magnet structure forces a completely new ion source design, not an extension of an existing design.

Beam Direction

2. VENUS serves as test bed to understand the transport of high current heavy ion 12 beams



Venus at 18 GHz out performances AECR-U especially for heavy ions





High performance fully permanent magnet ECR ion source (commercially available)

SUPERNANOGAN



2 mA of H+
150 eµA O⁶⁺
350 eµA of Ar⁸⁺

- + High Frequency 14.5 GHz
- Fully permanent magnet
- Compact, but
 - Performance limited
 - Ovens difficult
 - Beam transport difficult
- Compact RF system (Traveling Wave Tube) Power limited (400 W)
- Especially suitable for high voltage platforms

High performance fully permanent magnet ECR ion source (continue)





Ref.: C. Bieth, J. L. Bouly, J. C. Curdy, S. Kantas, **P. Sortais**, P. Sole, and J. L. Vieux-Rochaz Rev. Sci. Instrum. **71**, 899 (2000)

A conventional ECR lon source offers more operational flexibility and higher intensities than fully permanent sources



AECR-U Ions Source

Radial probe

(direct insertion)





Comparison of highest performance conventional and fully permanent ECR ion sources



Beam Transport



- Space charge dominated beams
- Charge state distribution for each species present at extraction (each contribution must be taken into account correctly)
- Different focusing properties for each M/Q
- Emittance contribution due to the high solenoid field at the extraction



The ECR Ion Source Emittance dominated by the magnetic field at extraction



M. Leitner *et al*: "*Design of the Extraction System and Beamline of the Superconducting ECR Ion Source VENUS*",Proc. of the 2001 Particle Accelerator Conference (PAC 2001), Chicago, Illinois, June 2001

VENUS Low Energy Beam Transport



Emittance Measurements combined with Ion Beam simulations are essential for understanding the ion beam transport for ECR ion source NUS theoretical emittance (1rms) due to the magnetic field 70 0.2 60 220euA Ar11+ 40 15 keV 0.15 •Plasma 0.10 pi mm mrad X' [mrad] 20 stability Tuning 0 0.1 Optics -20 -40 0.05 -60 -70 -20 -15 -10 20 -5 10 15 Ω 2 8 10 12 14 4 6 X [mm]

- Essential for providing very high quality beams as required for precision measurements
- RIA R&D will provide an essential data base for the beam transport



Experimental requirements are needed for the optimum design of the injector

- Injector system type (Power and Space available)
- Intensity needed
- Energy range
- Ion species
- Purity of lons
- CW or pulsed
- Timing (chopping)
- Beam quality
 - Beam Noise
 - Stability
 - Spot size

High Intensity single charge lon Source

Maybe required for some low cross section experiments

High charge state ECR

- Conventional/permanent magnet
- Charge state can vary to change energy

Charge state selection

Beam transport

- ECR sources are ideal sources for an underground accelerator
 - Demonstrated performance record on accelerator
 - High Reliability and Flexibility
 - Have to decide which kind of ECR is best suited (depends mainly on intensity required)
- R&D (simulations and experiments) for the ECR ion beam transport would be beneficial
 - To assure very high quality beams
 - Build injector system to measure beam parameter
 - overlap with RIA R&D